

**PLASMA REACTOR HAVING RF POWER APPLCIATOR AND A DUAL-PURPOSE
WINDOW**

ABSTRACT OF THE INVENTION

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In a plasma reactor including a reactor chamber, a
workpiece support for holding a workpiece inside the chamber
during processing and an inductive antenna, a window
electrode proximal a wall of the chamber, the antenna and
10 wall being positioned adjacently, the window electrode
being operable as (a) a capacitive electrode accepting RF
power to capacitively coupled plasma source power into the
chamber, and (b) a window electrode passing RF power
therethrough from said antenna into the chamber to
15 inductively couple plasma source power into the chamber.